Electronic Patent Application Fee Transmittal Application Number: 10657505						
Application Number:	10657505					
Filing Date:	08-Sep-2003					
Title of Invention:	Method of manufacturing a contact interconnection layer containing a metal and nitrogen by atomic layer deposition for deep sub-micron semiconductor technology					
First Named Inventor:	Chii-Ming Wu					
Filer:	David M. Odell/Denise Wilson					
Attorney Docket Number:	TS01-1247					
Filed as Large Entity						
Utility Filing Fees						
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)	
Basic Filing:						
Pages:						
Claims:						
Miscellaneous-Filing:						
Petition:						
Patent-Appeals-and-Interference:						
Post-Allowance-and-Post-Issuance:						
Extension-of-Time:						
Extension - 1 month with \$0 paid		1251	1	120	120	

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
	Total in USD (\$)			120